

PATENT Attorney Docket No. 4329.2437-02

#### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re U.S. Patent No.: 7,125,584 B2		)
Inventor: SHINICHI ITO		)
Issue Date.: October 24, 2006		)
For:	METHOD FOR FORMING A LIQUID FILM ON A SUBSTRATE	)

Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450

Certificate

DEC 0 1 2006

of Correction

Sir:

#### REQUEST FOR CERTIFICATE OF CORRECTION

Pursuant to 35 U.S.C. § 254, and 37 C.F.R. § 1.322, this is a request for a Certificate of Correction in the above-identified patent. The mistakes identified in the appended Form occurred through the fault of the Patent Office, as clearly disclosed by the records of the application which matured into this patent.

Applicant is requesting correction of the Letters Patent so as to correct patent claims 1-3 to include the changes contained in the Supplemental Amendment filed on December 22, 2005. In that Supplemental Amendment, Applicants amended application claims 15-17, which correspond to patent claims 1-3. In the Notice of Allowability mailed January 10, 2006, the Examiner stated that the "after final amendment filed December 22, 2005" overcame all pending rejections. Therefore, patent claims 1-3 should conform to amended claims 15-17 as presented in the Supplemental Amendment filed December 22, 2005. This Request is therefore filed to request correction of patent claims 1-3 to conform them to application claims 15-17 as amended in the Supplemental Amendment filed December 22, 2005.

Two (2) copies of PTO Form 1050 are appended. The complete Certificate of Correction involves three (3) pages. Issuance of the Certificate of Correction containing the correction is earnestly requested.

Please charge any required fees not included herewith to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW, GARRETT & DUNNER, L.L.P.

Dated: 11/29/06

Bv·

Richard V. Burg

Reg. No. 31,744

PATENT NO.

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**APPLICATION NO.:** 

10/697,436

**ISSUE DATE:** 

October 24, 2006

**INVENTOR:** 

Ito

It is hereby certified that an error or errors appear in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Claims 1-3, column 16, lines 16-46, delete claims 1-3 and substitute the following claims 1-3 therefor:

1. A liquid film forming method of dropping a liquid to be spread on a substrate to be processed from a dropping nozzle or dropping nozzles of a dropping unit onto the substrate, and then moving the dropping unit and the substrate relatively while keeping the liquid dropping on the substrate, so as to form a liquid film on the substrate,

wherein the relative movement of the dropping unit and the substrate is composed of straight movement along a file direction in which the dropping unit passes from one end side of the substrate through an upper space over the substrate to the other end side of the substrate, and movement along a rank direction, and

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a distance between a dropping start position on the substrate and an edge of the substrate closest to the dropping start position is relatively larger than a distance between a dropping end position on the substrate and an edge of the substrate closest to the dropping end position, and a distance between an end of the liquid film and an edge of the substrate closest to the end of the liquid film gradually decreases from the dropping start position to the dropping end position.

2. The liquid film forming method according to claim 1, wherein the distance between the end of the liquid film and the edge of the substrate closest to the end of the liquid film is decided based on a distance that the liquid flows on the substrate after the dropping of the liquid on the substrate.

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3. The liquid film forming method according to claim 1, wherein the distance between the end of the liquid film and the edge of the substrate closest to the end of the liquid film is a distance that the liquid flows on the substrate after the dropping of the liquid from the end of the liquid film to the end of the substrate closest to the end of the liquid film.

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wherein the relative movement of the dropping unit and the substrate is composed of straight movement along a file direction in which the dropping unit passes from one end side of the substrate through an upper space over the substrate to the other end side of the substrate, and movement along a rank direction, and

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2. The liquid film forming method according to claim 1, wherein the distance between the end of the liquid film and the edge of the substrate closest to the end of the liquid film is decided based on a distance that the liquid flows on the substrate after the dropping of the liquid on the substrate.

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3. The liquid film forming method according to claim 1, wherein the distance between the end of the liquid film and the edge of the substrate closest to the end of the liquid film is a distance that the liquid flows on the substrate after the dropping of the liquid from the end of the liquid film to the end of the substrate closest to the end of the liquid film.

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